

FIG. 1 is a schematic diagram of a microwave plasma reactor system. The system includes a 27 MHz source (54) connected to a matching network (56). The matching network is connected to a BPF (58) which is connected to the reactor (10). The reactor (10) is a rectangular chamber with a top flange (12) and a bottom flange (14). The top flange (12) has a central port (16) for process gas (22) and a side port (18) for a 2 MHz source (60). The bottom flange (14) has a central port (20) and a side port (24). The reactor (10) is connected to a 2 MHz source (60) via a matching network (62) and a BPF (64). The reactor (10) is also connected to a 2 MHz source (60) via a matching network (62) and a BPF (64).

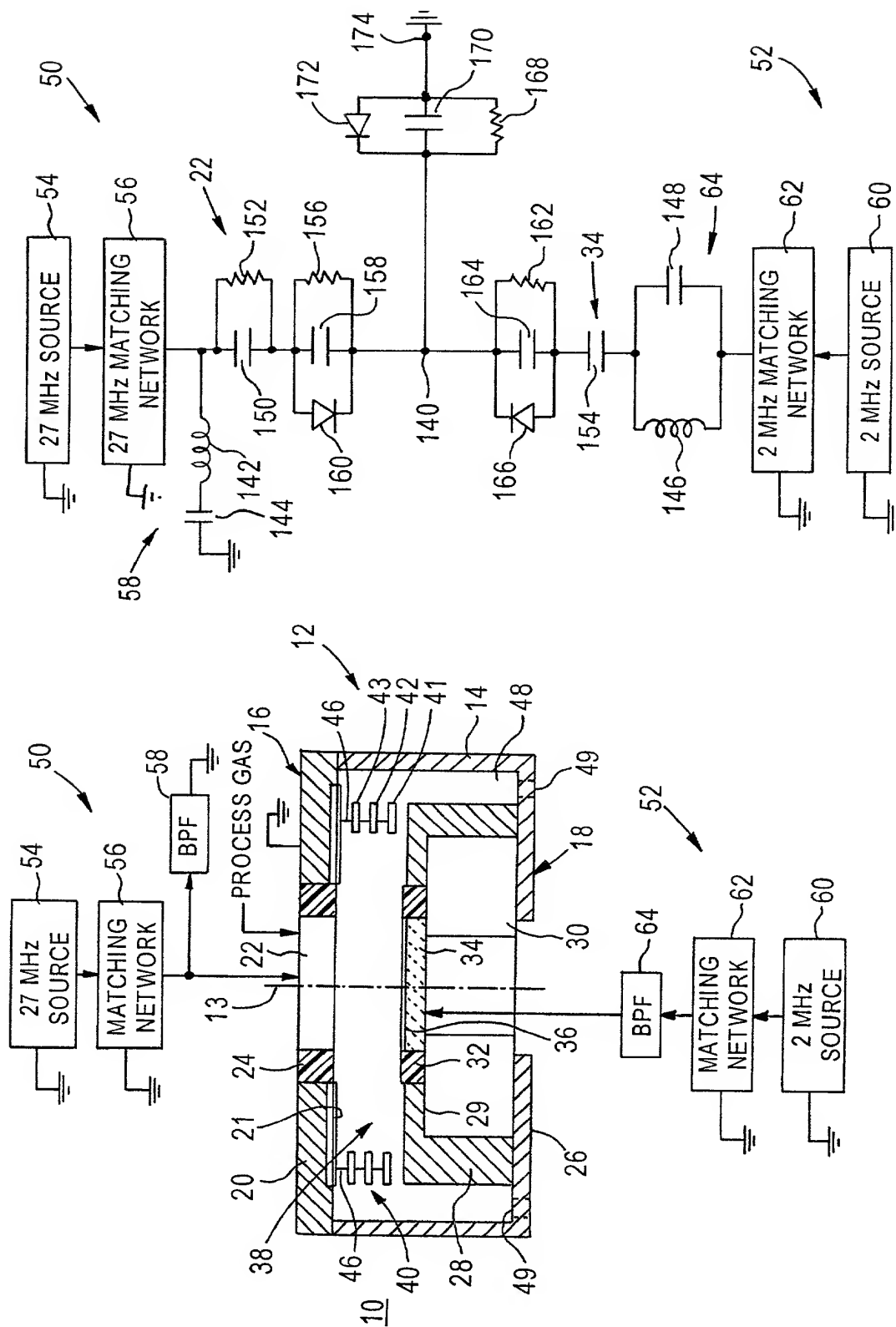


FIG. 1

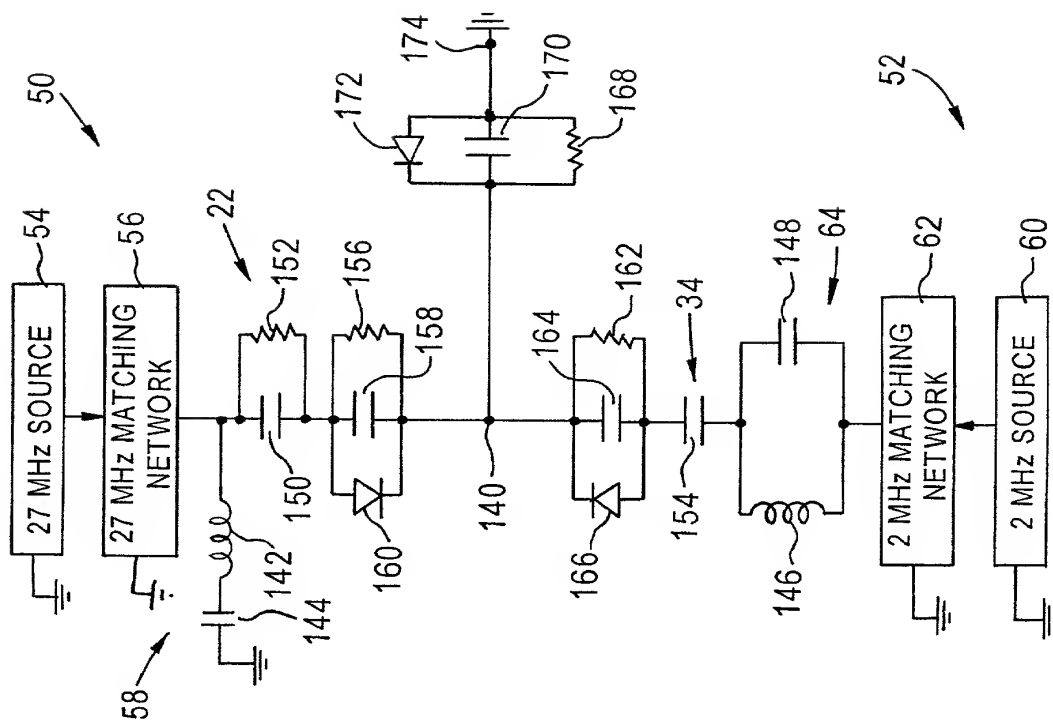


FIG. 3

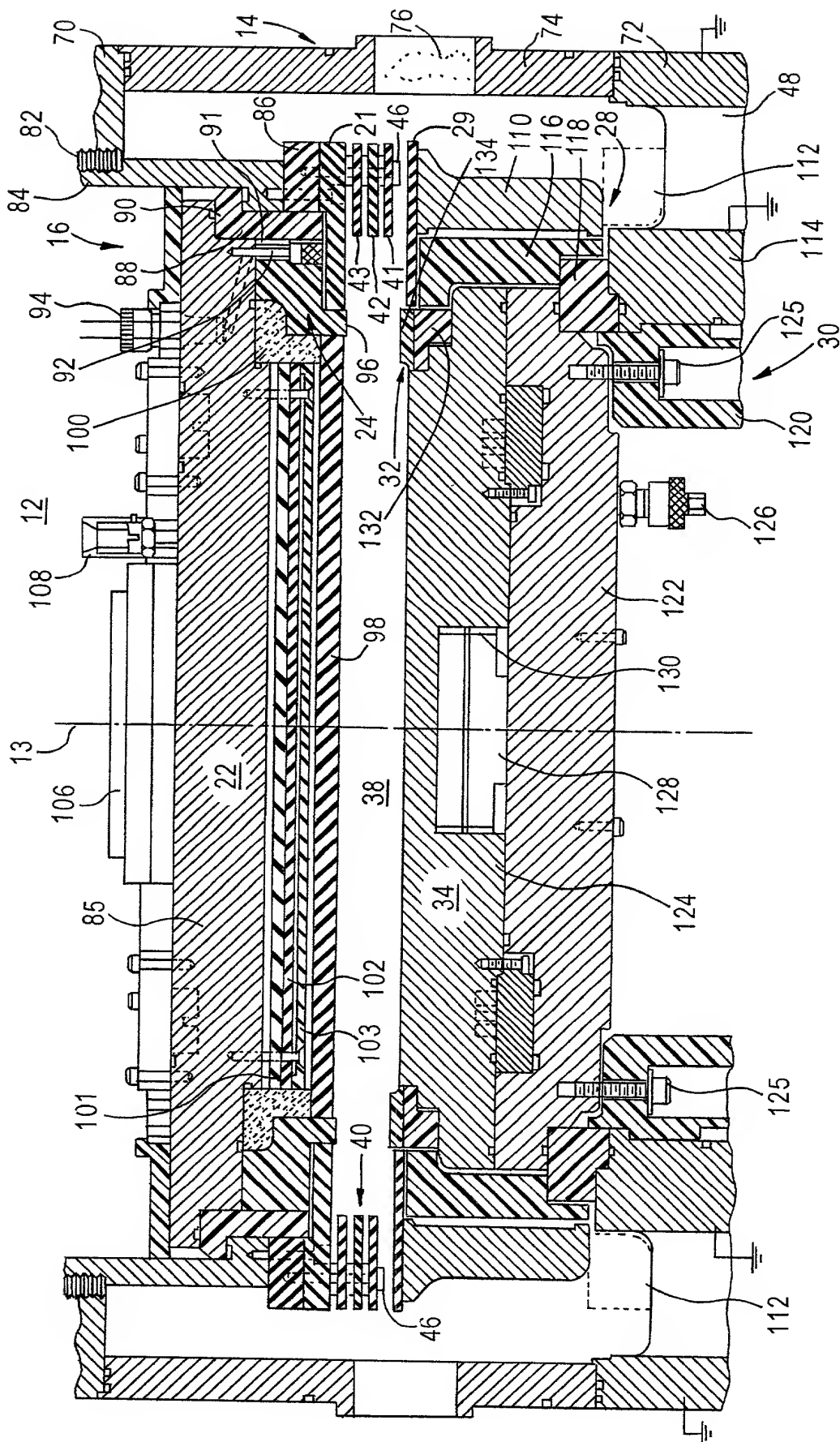


FIG. 2